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# Optimizing Pulse Conditions for Enhanced Memory Performance of Se-Based Selector-Only Memory

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**ABSTRACT** In this study, we investigated the effect of pulse falling time ( $T_{\text{fall}}$ ) on the electrical characteristics of SiGeAsSe-based selector-only memory (SOM) devices. Our experimental results demonstrate that increasing the  $T_{\text{fall}}$  leads to an increased threshold voltage ( $V_{\text{th}}$ ) and reduced  $V_{\text{th}}$  drift in SiGeAsSe devices. The optimized devices exhibit a remarkable memory window ( $> 1$  V) and significantly suppressed drift characteristics ( $\sim 10$  mV/dec.). Electrical measurements at high temperatures demonstrate that  $T_{\text{fall}}$  is one of the important factors in material relaxation, and these improvements are attributed to the intentionally induced reconfiguration of the chalcogenide film. Furthermore, our results reveal that a suitable  $T_{\text{fall}}$  can effectively mitigate the degradation of the memory window at high temperatures. These findings afford valuable insights into the role of material relaxation in SOM devices, potentially aiding the development of high-performance memory devices.

**INDEX TERMS** Chalcogenide, cross-point array (XPA), ovonic threshold switch (OTS), ReRAM, selector-only memory (SOM).

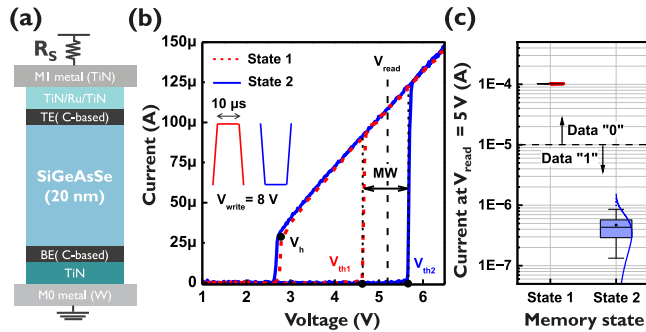
## I. INTRODUCTION

To satisfy the increasing demand for high-performance memory in modern computing systems, a selector-only memory (SOM) operating with a chalcogenide-based ovonic threshold switch (OTS) has been proposed [1], [2], [3]. Owing to its simple structure, the cross-point array (XPA) with SOM can overcome various problems, such as void formation and thermal disturbances, which are found in conventional XPA composed of phase change memory (PCM) and OTS [4]. Moreover, its single-layer structure enables the implementation of a vertical-XPA (V-XPA) architecture for ultra-high-density memory devices [5].

SOM devices operate based on the polarity-induced threshold voltage ( $V_{\text{th}}$ ) shift phenomenon of the OTS [6]. A

write pulse with the same polarity as the read pulse results in a low  $V_{\text{th}}$  (State 1), whereas an opposite polarity induces a high  $V_{\text{th}}$  (State 2). Although SOM devices offer fast operating speed and excellent cycling endurance compared to traditional PCM-based devices [7], they still face several challenges, such as an insufficient memory window (MW).

Furthermore, material relaxation in chalcogenide-based memory devices is a critical issue that must be overcome to utilize SOM as a non-volatile memory component. This relaxation occurs due to the gradual disappearance of unstable homopolar bonds (e.g., Ge-Ge) present within the chalcogenide materials [8]. The short-range ordering due to this thermodynamic stabilization leads to an increase in film resistance and can result in operation failures during read



**FIGURE 1.** (a) Schematic diagram and (b) typical AC I-V characteristics of a fabricated Se-based SOM device. (c) Current values at  $V_{\text{read}}$  based on the state of the memory device.

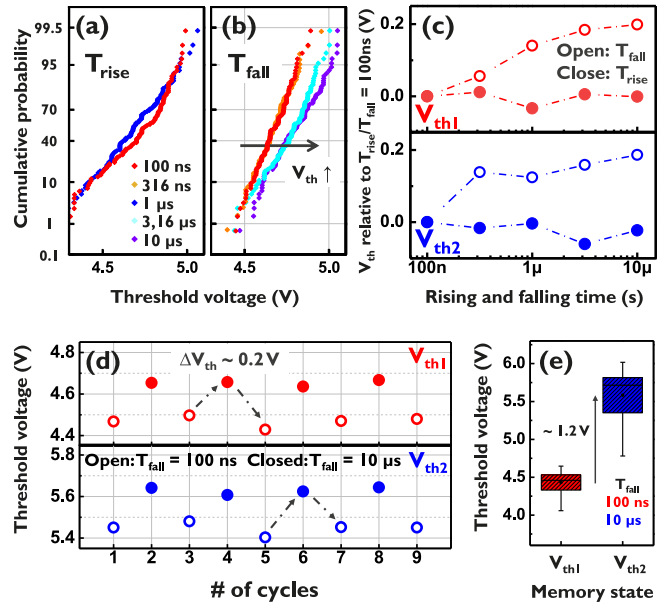
and write process. Therefore, it is necessary to identify the important factors that cause material relaxation and develop techniques to control them precisely.

To address these challenges and better understand the material relaxation in SOM devices, this study investigated the effect of falling time ( $T_{\text{fall}}$ ) on the memory properties. Our results demonstrate that  $T_{\text{fall}}$  modulation enables MW optimization by controlling the  $V_{\text{th}}$ . In addition, by evaluating the  $V_{\text{th}}$  drift under various  $T_{\text{fall}}$  conditions, we found that increasing  $T_{\text{fall}}$  can successfully suppress the drift process. High-temperature (HT) measurements further reveal that the improved electrical performance is attributed to the intentionally accelerated relaxation of the chalcogenide film. Based on our experimental results, we propose a material relaxation model driven by the  $T_{\text{fall}}$  effect, providing deeper insights into the switching mechanisms. Our study offers practical guidelines for optimizing the applied pulse conditions, which can serve as a key factor in maximizing the memory performance and reliability of SOM devices.

## II. EXPERIMENTAL DETAILS

An amorphous SiGeAsSe layer was deposited between a C-based top electrode (TE) and bottom electrode (BE) on a 300 mm wafer by using physical vapor deposition sputtering [2]. The stack was patterned into a pillar, with a critical dimension of 60 nm. An on-chip resistor ( $R_s = 2.5$  k $\Omega$ ), acting as a current limiter, was integrated into the device (Fig. 1(a)). Electrical characterization was performed using a Keysight B1530A Waveform Generation-Fast Measurement Unit (WGFMU).

For the write operation of the SOM, we applied square pulse with amplitude of  $V_{\text{write}} = 8$  V and a width of 10  $\mu\text{s}$ . To evaluate the effects of the rising time ( $T_{\text{rise}}$ ) and  $T_{\text{fall}}$ , these times varied from 100 ns to 10  $\mu\text{s}$  (denoted as T1 to T5). After the write operation, the  $V_{\text{th}}$  was extracted using a 10  $\mu\text{s}$  triangular pulse with  $V_{\text{applied}} = 10$  V. Fig. 1(b) shows typical AC current–voltage (I–V) characteristics of the fabricated SOM device. The device exhibited two distinct  $V_{\text{th}}$  values depending on the polarity of the applied write pulses ( $V_{\text{th1}}$  for State 1 and  $V_{\text{th2}}$  for State 2). Upon application of a read voltage ( $V_{\text{read}}$ ) between the two  $V_{\text{th}}$  values, the current varied according to the memory state (Fig. 1(c)).



**FIGURE 2.**  $V_{\text{th}}$  as a function of (a)  $T_{\text{rise}}$  and (b)  $T_{\text{fall}}$  of writing pulses. (c) Changes of  $V_{\text{th}}$  with  $T_{\text{rise}}$  and  $T_{\text{fall}}$  for two different memory conditions. The presented  $V_{\text{th}}$  represent the average values extracted from 100 cycling measurements for each pulse condition.  $V_{\text{th}}$  was unaffected by  $T_{\text{rise}}$  but strongly depends on  $T_{\text{fall}}$ . (d) Average value of  $V_{\text{th1}}$  and  $V_{\text{th2}}$  with alternate sequences of  $T_{\text{fall}}$ . The dependency of  $V_{\text{th}}$  on  $T_{\text{fall}}$  was reproducible and reversible. (e) MW at optimized  $T_{\text{fall}}$  for each state, showing excellent characteristics over 1.2 V.

## III. RESULTS AND DISCUSSIONS

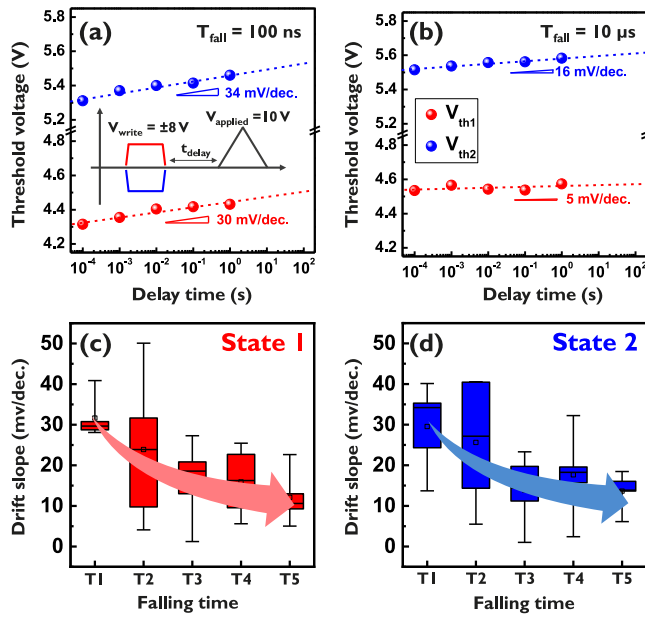
### A. ELECTRICAL PROPERTIES UNDER VARIOUS PULSE CONDITIONS

Figs. 2(a) and 2(b) show the distribution of  $V_{\text{th}}$  across 100 cycles on a representative device, corresponding to varying  $T_{\text{rise}}$  and  $T_{\text{fall}}$ , respectively. Evidently,  $V_{\text{th}}$  was not affected by  $T_{\text{rise}}$  (Fig. 2(a)) but was strongly dependent on  $T_{\text{fall}}$  (as  $T_{\text{fall}}$  increased,  $V_{\text{th}}$  also increased; Fig. 2(b)) [9], [10]. These trends were consistent regardless of the memory state (Fig. 2(c)). These results indicate that  $T_{\text{fall}}$  is the determining parameter for  $V_{\text{th}}$ .

To verify whether  $V_{\text{th}}$  can be reversibly modulated, write pulses with  $T_{\text{fall}}$  of 100 ns and 10  $\mu\text{s}$  were alternately applied. As shown in Fig. 2(d),  $V_{\text{th1}}$  resulting from  $T_{\text{fall}} = 100$  ns and  $T_{\text{fall}} = 10$   $\mu\text{s}$  differ by 0.2 V ( $\Delta V_{\text{th}} \sim 0.2$  V), with the shifts in  $V_{\text{th}}$  appearing repeatedly. These modulations with  $T_{\text{fall}}$  can be utilized to maximize the MW of SOM devices. By applying the shortest  $T_{\text{fall}}$  during the write operation of State 1 and the longest  $T_{\text{fall}}$  during the write operation of State 2, the  $V_{\text{th}}$  difference can be increased, improving the MW over 1.2 V (Fig. 2(e)).

### B. $V_{\text{th}}$ DRIFT CHARACTERISTICS AS A FUNCTION OF $T_{\text{fall}}$

The drift phenomenon in chalcogenide-based memory and selector devices can be evaluated by measuring the dependency of  $V_{\text{th}}$  on the delay time ( $t_{\text{delay}}$ ) between write and read operations [11]. In this case, the  $V_{\text{th}}$  drift follows the



**FIGURE 3.**  $V_{th}$  drift as a function of  $t_{delay}$  at (a) T1 (= 100 ns) and (b) T5 (= 10  $\mu$ s). As  $T_{fall}$  of writing pulses increased, the drift characteristic was successfully suppressed. Drift slope with  $T_{fall}$  in (c) State 1 and (d) State 2, showing that drift improved as  $T_{fall}$  increased regardless of the memory state.

equation below:

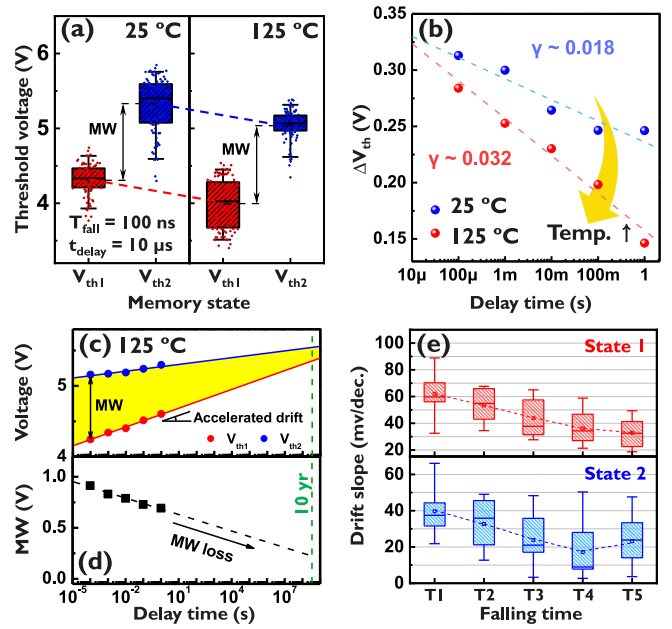
$$V_{th} = V_{th0} + \delta * \log\left(\frac{t}{t_0}\right) \quad (1)$$

where  $V_{th0}$  and  $t_0$  are material constants, and  $\delta$  is the characteristic exponent that controls the  $V_{th}$  drift [12]. We investigated the effect of  $T_{fall}$  on the drift by evaluating the device properties under various  $T_{fall}$  conditions. As shown in **Fig. 3(a)**, with a short  $T_{fall} = 100$  ns, the  $V_{th}$  drift was approximately 30 mV/dec. for States 1 (red dots) and 2 (blue dots). For longer  $T_{fall} = 10 \mu$ s, the drift characteristics improved dramatically, regardless of the memory state (**Fig. 3(b)**). The SOM devices with optimized pulse condition exhibited an excellent  $V_{th}$  drift of less than 10 mV/dec. at a  $T_{fall}$  of 10  $\mu$ s.

**Fig. 3(c)** and **Fig. 3(d)** show the drift slopes under various  $T_{fall}$  conditions for each memory state in 5 different dies. As  $T_{fall}$  increased from 100 ns to 10  $\mu$ s, the drift improved by approximately 66%. Owing to the improvement in the drift characteristics under long  $T_{fall}$  operating condition, the SOM device can prevent retention failure.

### C. TEMPERATURE DEPENDENCY OF $T_{fall}$ EFFECT

To understand the effect of  $T_{fall}$  on the amorphous chalcogenide films, HT measurement was performed. **Fig. 4(a)** shows the electrical characteristics of the SOM at 25  $^{\circ}$ C and 125  $^{\circ}$ C.  $V_{th}$  decreased at HT owing to accelerated electron hopping [13], [14]. Under a short  $t_{delay}$ , the MW remained stable regardless of the temperature (MW = 1 V). **Fig. 4(b)** illustrates the variation in  $\Delta V_{th}$  with  $t_{delay}$  and

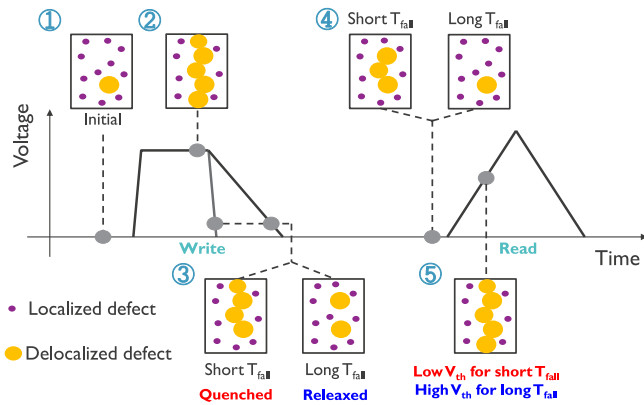


**FIGURE 4.** (a) 100 cycles of  $V_{th}$  and MW at 25  $^{\circ}$ C and 125  $^{\circ}$ C. (b)  $\Delta V_{th}$  as a function of  $t_{delay}$ . At 125  $^{\circ}$ C,  $\Delta V_{th}$  decreased rapidly as  $t_{delay}$  increased. (c)  $V_{th}$  drift characteristics and (d) MW as a function of  $t_{delay}$  at 125  $^{\circ}$ C ( $T_{fall} = 100$  ns). MW decreased dramatically as  $t_{delay}$  increased. (e) Drift slope at 125  $^{\circ}$ C with various  $T_{fall}$ .  $V_{th}$  Drift and MW can be improved at HT from  $T_{fall}$  adjustment.

temperature, showing that  $\Delta V_{th}$  decreased as  $t_{delay}$  increased. This trend became more dramatic at HT. As mentioned in Section A,  $\Delta V_{th}$  is defined as “ $V_{th}$  at  $T_{fall} = 10 \mu$ s -  $V_{th}$  at  $T_{fall} = 100$  ns”. This means that  $\Delta V_{th}$  serves as a parameter representing the effect of  $T_{fall}$ . Therefore, the tendency for  $\Delta V_{th}$  to decrease with the increase in  $t_{delay}$  and temperature indicates that, with the increase of these factors, the influence of  $T_{fall}$  on the chalcogenide film is reduced, explaining the mechanism behind the improved electrical properties.

Temperature and  $t_{delay}$  are key factors in determining the relaxation of the chalcogenide film. As  $t_{delay}$  increased, material relaxation occurred in the chalcogenide film, which was further accelerated at HT [15]. Therefore, based on  $t_{delay}$  and temperature dependence of  $\Delta V_{th}$ , it can be confirmed that  $T_{fall}$  is another important factor influencing material relaxation.

**Fig. 4(c)** depicts the  $V_{th}$  drift as a function of  $t_{delay}$  at 125  $^{\circ}$ C. The drift characteristics exhibit different  $t_{delay}$  dependencies depending on the memory state, along with different temperature acceleration [16]. Notably,  $V_{th1}$  exhibited more rapid drift (compared to  $V_{th2}$ ), leading to a reduction in MW as  $t_{delay}$  increased (**Fig. 4(d)**). This accelerated drift significantly deteriorates the retention properties. **Fig. 4(e)** shows the drift slope as a function of  $T_{fall}$  at HT, measured across 7 different dies. Drift can be improved by increasing  $T_{fall}$  in both memory states. Modulating these drift characteristics can improve device retention.



**FIGURE 5.** Schematic showing the material relaxation mechanism of  $T_{fall}$ . By applying a writing pulse having sufficient  $T_{fall}$ , the drift characteristics of the SOM devices can be significantly improved.

## D. MECHANISM OF MATERIAL RELAXATION DRIVEN BY $T_{fall}$

The physical mechanism underlying these phenomena is illustrated in Fig. 5, which shows a schematic of  $T_{fall}$ -induced material relaxation. After the forming process, a portion of delocalized defects remains within the chalcogenide film, as shown in the initial state in Fig. 5. When a write pulse is applied, localized defects transition into delocalized defects under the external electric field, switching the device to a low-resistance state. During the switch-off phase, these delocalized defects lose stability as the external electric field is removed and revert to initial localized defects [17].

For a short  $T_{fall}$ , insufficient time for transition causes delocalized defects to remain in a “quenched” state. In contrast, a longer  $T_{fall}$  allows adequate time for delocalized defects to revert back to localized defects and promotes the material relaxation via electrical and thermal effects [18]. Consequently, devices with a long  $T_{fall}$  exhibit a higher  $V_{th}$  in subsequent switching processes due to the reduced number of delocalized defects. Furthermore, even after a short  $t_{delay}$ , devices with a long  $T_{fall}$  demonstrate improved drift characteristics, as the chalcogenide film undergoes sufficient relaxation during switch-off phase.

## IV. CONCLUSION

We demonstrated the impact of  $T_{fall}$  on the electrical properties of chalcogenide-based SOM devices. Our findings demonstrate that  $T_{fall}$  plays a crucial role in optimizing the performance of SOM devices. By increasing  $T_{fall}$ , we achieved a significant increase in  $V_{th}$  and a substantial reduction in drift, leading to a more stable and reliable memory operation. From the HT measurement, we revealed that  $T_{fall}$  is an essential parameter affecting material relaxation and confirmed that improvement in device performance could be attributed to intentional short-range ordering driven by increased  $T_{fall}$ . As a result of these changes, we have successfully improved the device characteristics without imposing additional circuit burdens. This understanding of the role of material relaxation can address the existing

challenges in SOM devices for the development of high-performance memory technologies.

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